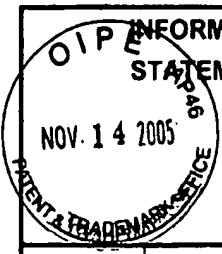


Sheet	1	of	1	Attorney Docket	UBAT1530
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Examiner Initials	Cite No.	FOREIGN PATENT DOCUMENTS			Publication Date MM-DD-YYYY (Number 43)	Name of Patentee or Applicant of Cited Document
		Country Code	Number	Kind Code (if known)		
Examiner Signature	<i>Arshata Datta</i>			Date Considered	<i>March 13, 2006</i>	

				Application Number	10/716,770
				Filing Date	November 19, 2003
				First Named Inventor	Guillorn
				Group Art Unit	2881
				Examiner Name	Fernandez, Kalimah <i>Nikita Wells</i>
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Examiner Signature	<i>Nikita Wells</i>			Date Considered	<i>March 13, 2006</i>

INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/716,770
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Sheet	2	of	2	Attorney Docket Number	UBAT1530
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